

**Amendment to the Claims:****Listing of Claims:**

Claim 1 (currently amended) A process to prepare stoichiometric-nanostructured materials, comprising[[;]] :

generating a plasma;

forming an [[“]]active volume[["]] through introduction of an oxidizing gas into the plasma[[,]] before the plasma is expanded into [[a]] field-free zone[[,]]; [[either (1) in a region in close proximity to a zone of charge carrier generation, or (2) in a region of current conduction between field generating elements, including the surface of the field generation elements; and

transferring energy from the plasma to a precursor material or materials and forming in the “active volume” at least one of stoichiometric-nanostructured materials and a vapor that may be condensed to form a stoichiometric-nanostructured material]] and introducing a precursor material into the active volume.

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